

12/03/01  
10006100  
JCS/100  
12/03/01

PATENT NUMBER and  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10006100	FILING DATE 12/03/2001	CLASS 156	SUBCLASS 438	GAU 345.3	EXAMINER ZEVIGUN
----------------------	---------------------------	--------------	-----------------	--------------	---------------------

\*\*APPLICANTS: Shepherd Robert; Caughran James;

\*\*CONTINUING DATA VERIFIED:  
*N/A 12/28/03*

\*\* FOREIGN APPLICATIONS VERIFIED:  
*N/A 12/28/03*

PG-PUB	DO NOT PUBLISH <input checked="" type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed		<input type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO
35 USC 119 conditions met		<input type="checkbox"/> yes <input type="checkbox"/> no	NOVEP015
Verified and Acknowledged Examiners's initials			
TITLE : Method and apparatus for plasma optimization in wafer processing			
U.S.DEP'T. OF COMM./PAT. & TM-PTO-436L(Rev. 12-94)			

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg.	Print Fig.
		Application Examiner		
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE		
WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368. Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.				

FILED WITH:  DISK (CRF)  CD-ROM  
(Attached in pocket on right inside flap)